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PATENT

**ELECTROMAGNETIC AND NUCLEAR RADIATION
DETECTOR USING MICROMECHANICAL SENSORS**

This invention was made with Government support under contract DE-AC05-84OR21400 awarded by the U.S. Department of Energy to Lockheed Martin Energy Systems, Inc. and the Government
5 has certain rights in this invention.

FIELD OF THE INVENTION

The present invention relates generally to the field of measuring and testing, and more
10 specifically, to the detection of nuclear and electromagnetic radiation using micromechanical sensors.

BACKGROUND OF THE INVENTION

15 The detection of electromagnetic and nuclear radiation has extensive commercial applications. A variety of detectors including photomultipliers, thermopiles, scintillation devices and solid state detectors are currently
20 used. For example, the thermopile type of detector has a very broad band response since it is based upon thermal conversion of energy absorbed. Unfortunately, this type of detector generally has a slow response time and cannot

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reasonably be manufactured as two-dimensional array detectors. Solid state detectors for the infrared region are based on semiconductor effects. This generally requires the device to
5 be kept at a cryogenic temperature to reduce thermal activation.

A technique that can detect infrared radiation without requiring temperature control, and that has broadband sensitivity and can be
10 made into two dimensional arrays, would have immediate relevance in a variety of industries, such as: aerospace, military and civilian surveillance, industrial monitoring, night vision systems, and collision avoidance systems.

15 Similar advantages can be stated for nuclear radiation detectors using micromechanical sensors. Uncooled, integrating detectors having single or arrayed detector elements that respond to absorbed nuclear
20 radiation would have immediate applications in health physics monitoring, mixed waste radiation, environmental monitoring and field screening.

Recently there has been a growth of
25 interest in micromechanical sensors.

Micromechanical sensors can consist of any of a class of suspended mass devices, such as microcantilever beams supported at one or multiple points, or suspended about their perimeter. For example, microcantilevers coated with metal on one side undergo bending due to differential thermal expansion of the coating metal and the coated cantilever (the "bimetallic effect"). Bending due to the bimetallic effect has been used for calorimetric detection of chemical reactions with picoJoule (pJ) sensitivity.

U.S. Patent No. 5,445,008 to Wachter et al. describes microbar sensors which employ microcantilevers oscillated by a piezoelectric transducer. A coating on the beam selectively adsorbs a target chemical, and accumulation of the chemical is manifest in a change of resonant frequency of the beam. This patent is incorporated herein by reference.

U.S. Patent No. 5,144,833 to Amer et al. describes an atomic force microscope that employs micromachined cantilevers. As a tip mounted on the cantilever moves over a surface, interatomic forces between the tip and the

surface induce displacement of the tip.

U.S. Patent No. 5,245,863 to Kajimura et al. describes another atomic force microscope in which a cantilever is fixed to a piezoelectric element. A semiconductor laser constitutes a
5 Fabry-Perot resonator between a mirror and a reflection cleavage plane. The resonator output varies in accordance with displacement of the cantilever.

10 U.S. Patent No. 5,347,226 to Bachmann describes an array spreading resistance probe which uses a microcantilever. A probe tip is formed in openings in the distal end of the cantilever. The probe tips are used to obtain
15 impurity profiles of semiconductors.

U.S. Patent No. 5,345,816 to Clabes et al. describes an integrated tip strain sensor for use in an atomic force microscope. The tip is formed by electron beam deposition.

20 The references noted above do not provide methods or devices for measuring atomic or electromagnetic radiations.

SUMMARY OF THE INVENTION

25 An object of the present invention is to

provide a detector which is capable of detecting a broad range of electromagnetic and nuclear radiations.

Another object of the present invention is
5 to provide a detector which is capable of detecting electromagnetic and nuclear radiations with picoJoule sensitivity.

Still another object of the present invention is to provide a radiation detector
10 which exhibits relatively fast response times.

Another object of the invention is to provide microcantilevers that are fabricated from materials that respond to impinging nuclear radiation that causes a change in mechanical
15 properties of the microcantilever. This response is the result of radiation damage in the microcantilever or in an applied coating on the microcantilever. Sensitizing materials can include various polymeric chemicals and solid
20 state materials that absorb nuclear radiation, such as crystalline silicon.

These and other objects of the invention are met by providing a method and apparatus for detecting electromagnetic and nuclear radiation
25 which includes exposing a cantilever to

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radiation, the cantilever having at least one physical parameter which varies in response to the radiation, monitoring changes in the at least one physical parameter, and correlating
5 changes in the at least one physical parameter to the presence of a type or quantity of radiation.

An illustrative embodiment of the invention provides for detection of electromagnetic
10 radiation using a micromechanical sensor. The micromechanical sensor comprises a microcantilever coated with one or more coating materials that react to electromagnetic radiation. As the coatings on the
15 microcantilever absorb electromagnetic radiation, the microcantilever bends, and/or undergoes a shift in resonance frequency.

Bending shifts, and resonance frequency changes are physical properties that can be
20 detected with high sensitivity detection methods taught herein. Such detection methods can be based on changes in optical, capacitive, electron tunnelling piezoelectric, or piezoresistive properties. A wide band of the
25 electromagnetic spectrum can be detected to

picoJoule sensitivity with one or more coated microcantilevers. Specific absorptive coatings can be used for selective sensitivity in specific wavelength bands. A micromechanical
5 sensor assembly comprising an array of coated microcantilevers provides detection resolution comparable to CCD arrays.

In another specific embodiment of the invention, microcantilevers are coated with
10 optical radiation sensitive polymers. The coated microcantilevers can be used as optical radiation dosimeters. Upon exposure to radiation, such a polymer-coated microcantilever bends due to internal stresses and its resonance
15 frequency increases due to stiffening. Physical properties of the polymer-coated microcantilever radiation dosimeters are monitored to detect optical radiation based on the measured properties responding to impinging
20 electromagnetic radiation.

Other objects, advantages, and salient features will be more apparent when considered with the following detailed description and drawing that are provided to facilitate the
25 understanding of the subject invention without

any limitation thereto.

BRIEF DESCRIPTION OF THE DRAWING

FIG. 1 is an enlarged, perspective view of
5 a cantilever sensor capable of detecting
radiation according to an embodiment of the
present invention;

FIG. 2 is a perspective view of the
cantilever depicted in FIG. 1 bending under
10 stress;

FIG. 3 is a plan view of a wafer containing
an array of microcantilevers according to the
present invention;

FIG. 4 is a vertical sectional view taken
15 along the line IV-IV of FIG. 3;

FIG. 5 is an enlarged perspective view of a
radiation detector according to another
embodiment of the present invention;

FIG. 6 is a perspective view of the
20 cantilever depicted in FIG. 5 bending due to a
radiation-induced change in the differential
stress of the microcantilever;

FIG. 7 is a schematic view for describing a
cantilever disposed with respect to a laser
25 diode and a position sensitive detector in an

optical detection arrangement;

FIG. 8 is a schematic view for describing a cantilever with a piezoresistive coating coupled to a resistance detector in a piezoresistive
5 detection arrangement;

FIG. 9 is a schematic view for describing a cantilever disposed within a capacitor in a capacitive detection arrangement;

FIG. 10 is a schematic view for describing
10 a cantilever disposed with respect to a laser diode, a position sensitive detector, and a modulator in a modulated detection arrangement;

FIG. 11 is a perspective view for describing a cantilever presenting a partial
15 metal film coating;

FIG. 12 is a perspective view for describing a cantilever coupled with a thermal insulator;

FIG. 13 is a perspective view for
20 describing a cantilever with a thermally-absorptive coating;

FIG. 14 is a graph for describing shifting of relative resonance as a function of ultraviolet exposure for a cantilever coated
25 with an optically sensitive material according

to an embodiment of the invention; and

FIG. 15 is a graph for describing
cantilever deflection as a function of
ultraviolet exposure for a cantilever described
5 with respect to FIG. 14.

DETAILED DESCRIPTION OF THE PREFERRED
EMBODIMENTS

10 For a better understanding of the present
invention, together with other and further
objects, advantages, and capabilities thereof,
reference is made to the following disclosure
and to the figures of the drawing, where like
15 reference characters designate like or similar
elements. In accordance with an embodiment of
the invention, radiation detection is based upon
absorption of radiation to cause physical
movement and changes in the mechanical resonance
20 of a microcantilever. These changes can be
sensitively detected as taught herein.

Referring to FIG. 1, a sensor according to
the present invention is generally referred to
by the numeral 20. The sensor 20 includes a
25 microcantilever 22 connected at its proximal end
to, and extending outwardly from, a base 24. A

coating 26 is formed on one of the surfaces of the microcantilever 22.

One particular embodiment utilizes metal coated microcantilevers such as those commonly
5 sized for atomic force microscopy (AFM), in which sub-Angstrom ($<10^{-10}$ meters) deflection sensitivity is routinely obtained. The metal-coated microcantilevers are typically 100-200 μm long, 0.3-3 μm thick and 10-30 μm wide and are
10 made out of a variety of materials such as silicon, silicon nitride, other semiconductors, or combinations thereof. Coating a side of the microcantilever with a different material, such as the metal film 26, makes the microcantilever
15 extremely sensitive to temperature variations due to the bimetallic effect, as previously defined. Such microcantilevers 20 undergo bending in response to temperature variations, as shown in FIG. 2. Thus, to detect infrared
20 radiation, for example, the infrared radiation would cause heating of the sensor, and differential thermal expansion of the sensor would result in a detectable bend in the microcantilever.

25 For optical detection, coating these

cantilevers with appropriate absorptive materials makes them bend when exposed to particular radiation (e.g., infrared, visible, or ultraviolet radiation). When the cantilever

5 20 is exposed to optical radiation, the temperature of the cantilever 20 increases due to absorption of radiation. The amount of cantilever bending is directly proportional in first order to the energy absorbed or to the

10 intensity of radiation exposure. As shown in FIGS. 3 and 4, these infrared detectors can be manufactured on a single wafer 28 in a two dimensional array 30 of five-hundred or more microcantilevers 32. This arrangement provides

15 spatial resolution comparable to current CCD detectors. One-hundred by one-hundred cantilever array or greater embodiments are contemplated.

Recent developments in scanning force

20 microscopy (SFM) have created a great interest in micromachining extremely sensitive cantilevers. Microcantilevers that can respond to forces as small as a few picoNewtons have been designed for imaging soft materials.

25 Microcantilevers with force constants as small

as 0.008 Newtons per meter (N/m) are commercially available. Typical dimensions of commercially available microcantilevers are 100-200 μm long and 20-40 μm wide. Most of the commercially available microcantilevers are triangular in shape. However, rectangular cantilevers are also presently commercially available.

Microcantilevers can be designed with much smaller force constants by controlling the geometry of the cantilever. These microcantilevers can be micromachined using routine techniques from the semiconductor industry. Therefore, microcantilevers specifically optimized for radiation detection can be mass produced at very small cost.

Microcantilevers undergo bending due to differential stress (the bimetallic effect) on the cantilever. For cantilevers having thin film coatings, the bending, z , due to differential stress, Δs , can be approximated by

$$z = (btl^2/4IY) \cdot \Delta s$$

(1)

where t is the cantilever thickness, l is the length, b is the width, I is the moment of

inertia, $Y = E^*/(1-\nu)$, ν is Poisson's ratio, and $E^* = E_1 E_2 / (E_1 + E_2)$ is the effective Young's modulus of the microcantilever (E_1 is Young's modulus for the substrate, E_2 is Young's modulus for the overlayer). This bending of the cantilever can be detected by optical techniques with sub-Angstrom sensitivity.

Silicon nitride microcantilevers with evaporated gold on one side undergo bending due to slight changes in temperature. This bending is due to the differential stress created by the differential thermal expansion of the silicon nitride and the gold overlayer. The differential stress due to thermal expansion of the materials can be written

$$\Delta s \approx l(E_1 \alpha_1 - E_2 \alpha_2) \Delta T \quad (2)$$

where ΔT is the temperature change and α_1 and α_2 are coefficients of thermal expansion of the substrate and the overlayer materials, which form the bimetallic strip.

Therefore, by measuring the bending distance z , the change in temperature can be determined as,

$$\Delta T \approx \frac{1}{3}[(t^2 Y) \cdot z] / [(l^3) \cdot (E_1 \alpha_1 - E_2 \alpha_2)] \quad (3)$$

where it is assumed that the temperature of the

base and the cantilever are the same.

The bending of the cantilever can be detected with high sensitivity using detection techniques used in scanning force microscopy (SFM). A commercially available SFM device is able to detect cantilever bending with subnanometer sensitivity. It is possible to increase the sensitivity to sub-Angstrom levels by optimizing the detection system.

Small temperature changes can be measured using bimetallic bending of the cantilever. For a commercially available silicon nitride cantilever with evaporated gold on one side using a bending deflection z of 0.1 nm in Eq. (1), the lowest value of ΔT is 10^{-10} K. By optimizing cantilever variables (Eqs. (1) and (2)) the sensitivity of detection can be improved by several orders of magnitude.

The bending of the microcantilever can be determined by several means, including optical, capacitive, or piezoresistive methods. Due to the very light mass ($\sim 10^{-9}$ g) and hence low thermal mass of the microcantilever, thermal equilibrium occurs very quickly and response

time can be in the microsecond range. The differential stress (Equation 4 above) of the microcantilever can also be determined by resonance techniques.

5 Referring to FIGS. 5 and 6, a sensor 32 includes a microcantilever 34 supported by a base 36. A metallic coating 38 is formed on one surface of the microcantilever 34 and a stress-sensitive or thermally-sensitive coating 40 on
10 the same surface or on another surface, as coating 38. The microcantilever 34 can be set into resonance by applying a mechanical oscillation to the base 36, as when the base is attached to a piezoelectric transducer. This
15 type of sensor is shown on our prior U.S. Patent No. 5,445,008, which is incorporated herein by reference.

As in the aforementioned patent, the base is driven by a variable frequency ac voltage to
20 determine the resonance characteristics. Natural oscillatory stimulation from ambient acoustic or thermal excitation phenomena can also be used to determine these resonance characteristics. The cantilever having a
25 stress-sensitive coating bends in response to a

thermal input (as shown in FIG. 6) as stresses develop in the coating 40, which cause a variation in the effective spring constant of the cantilever 34. Such a variation in spring constant causes a change in resonance frequency, and the change in resonance can be correlated to a detected presence of radiation. Bending of the cantilever can now be precisely determined by such a variation in resonance frequency. If the selected stress-sensitive coating 40 is directly responsive to thermal input, changes in its spring constant will also translate into variation in resonance frequency.

The resonance frequency as well as the magnitude and direction of bending of the cantilever can be determined electrically or optically. Referring to FIG. 7, an optical detector 42 incorporates the sensor 20 of FIG. 1, which includes a microcantilever 22, a base 24 and a coating 26. A diode laser (DL) 44 emits a laser beam 46 which is focused onto the free end of the microcantilever 22. The reflected beam is directed to a position sensitive detector (PSD) 48, which is operable to generate a position sensitive signal. The

position sensitive signal from the PSD is related to the extent and direction of cantilever bending. The position sensitive signal from the PSD can also be used to
5 determine the resonance frequency of the cantilever 20.

a Means for correlating the PSD signal to a detected ^{level} ~~level~~ and/or type of radiation is generally referred to in FIG. 7 as a correlation
10 circuit 50. The detected value may be displayed in various forms by a display device 52 coupled to the correlation circuit 50. Also, if desired, an oscillator 54 can be coupled to the base 24, with a reference signal being delivered
15 to the correlation circuit in a manner similar to that described in the aforementioned U.S. Patent No. 5,445,008.

a 55 Referring to FIG. 8, a radiation detector 54 uses the sensor 32 of FIG. 5, which includes
20 a microcantilever 34, a base 36, and a metallic coating 38. A second coating 40 is made of a piezoresistive material, which enables the resonance frequency and bending of the microcantilever 34 to be determined
25 electrically. This arrangement avoids the

complexity of optical arrangements. The resistance of the piezoresistive coating 40 changes as the cantilever bends. A resistance detector (RD) 56 is operable to monitor the
5 resistance and thereby determine the bending and resonance characteristics. For example, the resistance detector can provide a voltage signal which varies in accordance with microcantilever bending. The voltage signal can be displayed at
10 a display 58, which can take any conventional form.

The bending, as well as the resonance frequency of the microcantilever can also be determined by a capacitive technique illustrated
15 in FIG. 9. The radiation detector 60 includes a sensor 62 having a microcantilever 64 connected to a base 66 and a metallic coating 68 on the microcantilever. The microcantilever 64 is located inside a capacitor 70 having spaced
20 apart plates. The bending and contorting microcantilever changes the capacitance of the capacitor 70 as it moves. The changing capacitance is detected by a capacitance detector (CD) 72 which can produce an electrical
25 signal which varies in accordance with changes

in capacitance. The signal can be delivered to a display device 74 which can be of any conventional type. In an alternate embodiment, the microcantilever could serve as one pole of
5 the capacitor 70.

Referring to FIG. 10, a radiation detector 76 includes a sensor 78 having a microcantilever 80 connected to a base 82 and a metallic coating 84. An optical input 86 impinging on the
10 metallic coating 84 is modulated using a rotatable chopper or shutter 88. A modulator driver 90 rotates the modulator shutter (chopper) 88 by means of a drive signal.

A laser beam 92 is emitted by a laser diode
15 (LD) 94 and is reflected from the microcantilever 80 as a cyclic reflection signal. The cyclic reflection signal is detected by a position sensitive detector (PSD) 96 which is responsive to generate a PSD signal
20 98. As the cyclic reflection signal sweeps back and forth across the PSD 96, it is modulated by bending movement of the microcantilever 80 in response to the impinging optical signal 86. The modulated PSD signal 98 is passed to a lock-
25 in or phase detector (PD) 100 which can recover

the modulated bending signal using the drive signal from the modulation driver 90 as a reference. The detected modulated bending signal can be used to detect the existence and intensity of an impinging optical signal. A display 102 can be used to display the detected radiation.

The embodiment depicted in FIG. 10 serves to eliminate drift from the detection system (optical, capacitive, piezoresistive, or other methods) or any other instrumental source. Such modulated detection is generally two to six orders of magnitude more stable than equivalent d.c. methods.

FIG. 11 illustrates another embodiment of a sensor 104 in which a microcantilever 106 is connected to a base 108. A partial metallic coating 110 is formed on the microcantilever 106. This embodiment provides further maximized sensitivity of individual sensor elements over coatings covering the length of the microcantilever. This approach isolates the bimetallic element 110 from the heat sink in the base 108, so that thermal energy is not lost into the base 108. Equilibration occurs when

the extremely low mass bimetallic strip or coating 110 reaches thermal equilibrium, and all thermal energy is converted into thermal stress in the microcantilever 106.

5 Referring to FIG. 12, an alternative embodiment for a sensor 112 includes a microcantilever 114 connected to a base 116 and having a distal section 118 and a proximal section 120. The proximal section 120 is made
10 of a thermally insulative material. A metallic coating 122 is formed on the distal section 118. The thermally insulative material further reduces thermal loss into the base 116.

FIG. 13 illustrates a variation of the
15 embodiment of FIG. 12, in which a highly absorptive film or coating 124, such as gold black or Martin Marietta Black, is applied to the surface of the bimetallic coating 122 to increase η , the fraction of radiation flux
20 absorbed. This coating could be applied to the metallic coatings of the other embodiments described herein.

In accordance with another specific embodiment of the invention, micromechanical
25 detection of ultraviolet (UV) radiation at

picoJoule(pJ) levels uses microcantilevers coated with a UV sensitive polymer. Significant advantages of such micromechanical detection include high sensitivity and miniature size.

5 The technique can be embodied to detect radiation in other spectral regions by appropriate coating and design of cantilevers. An array of cantilevers with different sensitivities can be used as a compact, broad-
10 range detector. Sensitivity to light can be controlled by adjusting the geometry and coating of the cantilevers. For example, a variety of photoresist materials can be used to achieve different sensitivities under a range of
15 exposure conditions. An important application of this technique is for real-time characterization of photosensitive polymers used in integrated circuit fabrication.

Commercially available "V"-shaped (cross-
20 section) silicon cantilevers (180- μ m base to apex length) with a nominal effective spring constant of 0.06-N/m (Ultravers, from Park Scientific Instruments, Inc.) were used in tests exemplified herein. The cantilevers were coated
25 with a thin layer of optical adhesive, Norland

61 (Norland, New Brunswick, N.J.). Norland 61 is a clear, liquid, mercaptan-ester-based polymer that cures when exposed to UV light. A two-step curing process is generally used, comprising a short UV precure to set the material, followed by a longer UV cure to achieve full crosslinking. The maximum absorption is specified by the manufacturer to lie within the range of 354-378 nm.

10 Coating was achieved by placing a drop of the adhesive solution on a clean glass slide and sliding the cantilever into the droplet. Once the cantilevers were wetted, they were withdrawn from the droplet and allowed to air dry for two weeks in a covered Petri dish kept in the dark.

15 The deflection and resonance frequency of the microcantilevers were measured using a Multi-Mode Nanoscope III (Digital Instruments, Inc., Santa Barbara, CA) with the cantilevers positioned far away from any surfaces to avoid tip-surface interactions. Cantilevers were exposed to UV under ambient humidity and temperature. The UV source, a pencil-style mercury calibration lamp (Jelight Co., Laguna, CA), was placed directly below the cantilever at

distances from 1 to 10 cm. Radiant intensity at 1 cm was estimated to be 0.2 mW/cm² for the mercury line at 365 nm. Cantilever deflection was measured by monitoring the normalized error voltage between the top and bottom segment of a dual element position sensitive detector ($V_{\text{error}} = [A-B]/[A+B]$).

Deflection due to heating (from absorption of the Nanoscope diode laser light) is negligible for such a polymer-coated cantilever. The shift of cantilever resonance frequency due to exposure to UV light was observed by sweeping the excitation frequency of a piezoelectric element to which the cantilever was mounted.

The resonance frequency, ν , of a microcantilever can be described by

$$\nu = (1/2\pi)\sqrt{k/m^*} \quad (4)$$

where the effective mass m^* of the "V"-shaped cantilever is 0.18 m_b , m_b is the mass of the cantilever, and k is the effective spring constant. Under conditions of negligible damping, such as when the cantilever is oscillating freely in air, the resonance frequency is equal to the frequency of maximum oscillatory amplitude. The amount of polymer

deposited on the surface was calculated from the change in resonance frequency before and after coating.

The resonance frequency of microcantilevers
5 coated with photo cured polymer shifts dramatically when exposed to ultraviolet (UV) radiation. The magnitude and rate of this shift are dependent upon the power of the UV source and the distance between the source and the
10 cantilever.

FIG. 14 depicts the relative shift of resonance frequency (ν/ν_0) as a function of UV exposure time for a cantilever coated with Norland 61 optical adhesive for several exposure
15 conditions. Distances between the UV-source and the cantilever are 1.0 cm (top curve "A"), 7.8 cm (middle curve "B"), and 10.0 cm (bottom curve "C"). Each curve in FIG. 14 shows two distinct regions, a rapid change in resonance frequency
20 in a beginning region and a distinctly slower rate of change in a later region. For an exposure 1.0 cm from the UV source, the initial slope corresponds to a photometric sensitivity of approximately 100 pJ/Hz.

25 In addition to resonance frequency, static

deflection (bending) of the cantilever was also found to change with UV exposure, as shown by the curve in FIG. 15.

5 The frequency response shown in FIG. 14 and the static deflection response shown in FIG. 15 were taken simultaneously on the same cantilever (at 7.8 cm from the UV source). For all cantilevers tested, static deflection data also exhibited two distinct regions.

10 The shift in resonance frequency of these cantilevers upon exposure to UV radiation is due to changes in spring constant resulting from UV initiated crosslinking of the polymer coating. The two regions observed may be attributed to
15 the rapid precure process (steep initial slope in response to UV exposure) followed by the slower final crosslinking step (shallow secondary slope).

20 The slopes of the initial region for the different levels of UV exposure follow the general trend expected for a $1/d^2$ decrease in UV intensity as the distance, d , between the source and the cantilever is increased. However, the total relative frequency shift at the transition
25 between precure and cure steps decreases with

decreasing UV intensity, indicating that the coatings do not achieve the same ultimate rigidity. This may be the result of differences in degree of crystallinity for polymer films
5 undergoing shorter or longer periods of stretching during the curing process.

Surface stress changes as a result of crosslinking produce bending of the cantilever due to UV exposure. An inflection in the curve
10 shown in FIG. 15 occurs at an exposure time of approximately 1.2 minutes, while a break in the corresponding curing curve (C in FIG. 14) occurs at 2.7 minutes. The direction of initial deflection is consistent with swelling of the
15 polymer film attributable to exothermic expansion from rapid chemical reaction during precuring. As thermal equilibrium is reached and the rate of reaction begins to slow, the direction of deflection reverses as the polymer
20 density increases due to crosslinking.

The resonance frequency did not stop changing when the UV light was turned off, but continued to change for approximately one minute, perhaps due to slow completion of UV
25 initiated changes in the polymer coating.

This specific embodiment provides an effective means for achieving integrated measurement of radiation based on changes in resonance and bending of coated

5 microcantilevers. As a further specific embodiment of the invention, microcantilevers that are fabricated from materials responsive to impinging nuclear radiation can be used to detect nuclear radiation based on changes in the

10 mechanical properties of the microcantilever. Referring to FIG. 1, this response results from radiation-induced damage in the material which constitutes the microcantilever or in an applied coating 26 on the microcantilever 22. Sensitive

15 materials can include various polymeric chemicals and solid state materials that absorb nuclear radiation, such as crystalline silicon. Contributions of the invention can thus be used to construct extremely small, inexpensive, and

20 very sensitive micromechanical radiation dosimeters.

If a polymer coating material or other coating material offering reversible response to radiation exposure was used, then reversible

25 sensor response could also be achieved.

An array of cantilevers coated with differing polymers or other materials can be used to detect a wide range of radiant energies and intensities.

5 Other monitoring approaches can be used to eliminate potential interference from the optical transducer system, such as capacitive or piezoresistive sensing. In addition to photometric applications, coatings sensitive to
10 electrons or ions could be used to probe microchemical or physical phenomena.

 Embodiments of the invention could also be used to study the curing dynamics of photosensitive polymers, where the small size of
15 the sensor makes it especially attractive for profiling localized effects during semiconductor processing.

 There are numerous advantages provided by the invention: bending and resonance frequency
20 changes are inherently simple to detect, and the devices can be manufactured in arrays using conventional semiconductor methods. The present invention provides a much faster response time than conventional thermopile detectors. The
25 sensitivity afforded by embodiments of the

invention can be controlled by the geometry of the microcantilevers and coatings applied to the microcantilevers, which can affect broadband, narrow band, low pass, or high pass response.

5 With current micro-manufacturing technologies, an entire sensor embodiment is able to fit in a volume less than 100 μm on a side. A sensor array and control electronics can be housed in a standard transistor package.

10 The power requirement is estimated to be in the sub-mW range for individual sensors, which can be delivered by battery or photovoltaic means.

 Wide ranges of the electromagnetic spectrum can be detected using a sensor array

15 arrangement. Specific absorptive coatings enable selective sensitivity in specific wavelength bands; similar selectivity is possible with appropriate material selection for various nuclear particles and radiation.

20 Other applications of the invention include infrared radiation detection, satellite imagery, aerial surveillance, night vision, collision avoidance, ultraviolet detection, remote and micro-scale temperature measurements.

25 While several particular forms of the

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invention have been illustrated and described,
it will be apparent that various modifications
can be made without departing from the spirit
and scope of the invention.